

## WEST Search History

DATE: Thursday, May 18, 2006

Hide?	Set Name	Query	Hit Count
	<i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>		
<input type="checkbox"/>	L13	L12 and substrate	212
<input type="checkbox"/>	L12	L11 and silicon layer	213
<input type="checkbox"/>	L11	L9 and polishing	388
<input type="checkbox"/>	L10	L9 and HF dip	23
<input type="checkbox"/>	L9	L8 and oxide layer	1140
<input type="checkbox"/>	L8	L7 and wafer	2548
<input type="checkbox"/>	L7	L6 and (die or dice)	5554
<input type="checkbox"/>	L6	(SOI or silicon on insulator)	68203
<input type="checkbox"/>	L5	L4 and polishing	8
<input type="checkbox"/>	L4	L3 and (SOI or silicon on insulator)	12
<input type="checkbox"/>	L3	HF dip process	30
<input type="checkbox"/>	L2	(SOI or silicon on insulator) same interconnect line	81
<input type="checkbox"/>	L1	(SOI or silicon on insulator) and interconnect line	607

END OF SEARCH HISTORY

For 10/784566